

Appl. No. 09/617,127

REMARKS

Claims 1-5, 7-29, 31-33, 39-65, 67, 130-136, and 138-144 are pending in the present application. Applicants amend claim 27 to include original limitations and limitations of dependent claim 30. Independent claim 27 is believed to be allowable in view of the indication that claim 30 recites allowable subject matter.

Independent claim 63 has been amended to include the limitations of dependent claim 66. Independent claim 63 is believed to be allowable in view of the indication that claim 66 recites allowable subject matter. Applicants request allowance of claim 63 in the next Action.

Applicants hereby add new claims 141-143 which include the limitations of respective dependent claims 31, 64 and 65 and their respective base claims and any intervening claims. Such new claims 141-143 are believed to be allowable in view of the indication that the respective dependent claims recite allowable subject matter.

New claim 144 includes limitations of dependent claim 36 and the respective base claim. New claim 144 is believed to be allowable in view of the indication that dependent claim 36 recites allowable subject matter.

Applicants respectfully request allowance of all pending claims.

The Examiner is requested to phone the undersigned if the Examiner believes such would facilitate prosecution of the present application. The undersigned is available for telephone consultation at any time during normal business hours (Pacific Time Zone).

Appl. No. 09/517,127

Responsibly submitted,

Dated: 11/27/01

By:



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Reg. No. 39,833

Application Serial No. 09/517,127
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Inventor Scott E. Moore et al.
Assignee Micron Technology, Inc.
Group Art Unit 3723
Examiner T. Eley
Attorney's Docket No. MI22-1246
Title: "Semiconductor Processor Systems, A System Configured to Provide a Semiconductor Workpiece Process Fluid (As Amended)"

VERSION WITH MARKINGS TO SHOW CHANGES MADE ACCOMPANYING
RESPONSE TO OCTOBER 12, 2001 OFFICE ACTION

In the Claims

The claims have been amended as follows. Underlines indicate insertions and ~~strikeouts~~ indicate deletions.

27. (Twice Amended) A semiconductor processor system comprising:
a process chamber adapted to process at least one semiconductor workpiece;
a process fluid system including:
a mixer configured to mix a plurality of components of a process fluid;
a connection configured to supply the process fluid to the process chamber;
and
a sensor configured to output a signal indicative of at least one of the components and the process fluid; and
a control system coupled with the sensor and configured to control mixing of the components responsive to the signal; and
wherein the sensor is coupled with the connection and further comprising another

sensor coupled with a supply connection configured to supply one of the components to the mixer.

63. (Amended) A system configured to provide a semiconductor workpiece process fluid comprising:

a mixer configured to mix a plurality of components of a semiconductor workpiece process fluid;

a sensor configured to monitor turbidity of the semiconductor workpiece process fluid and to output a signal indicative of at least one of the components and the semiconductor workpiece process fluid; and

a control system coupled with the sensor and configured to control mixing of the components responsive to the signal.

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